TECHNICAL SPECIFICATIONS

HITACHI Inspire the Next

EA6000VX

Analyser:

- Benchtop EDXRF analyser.
- Rh or W target X-ray tube, depending on application (max. 50 W; 50 kV max, 1 mA max).
- · Top-down irradiation.
- 6 primary filter positions, programmable.
- 50 mm² Vortex® Silicon drift detector (SDD).

Element range:

- Mg (12) U (92).
- Na (11) U (92) with He purge option.

Collimators:

• Four, programmable: 0.2, 0.5, 1.2 and 3 mm (square).

Measurement focal distance:

• 5mm - 30mm.

Software:

- · X-ray Station control software.
- · Microsoft Windows 10 (64 bit) compatible.
- · Bulk FP and Bulk Calibration software.
- · Thin film FP and Thin film Calibration software.
- Auto-ID of x-ray peaks in spectrum, with comparison display.
- · Elemental mapping, with image/map overlap view.
- Graphical user interface available in 6 languages: Chinese Simplified, Chinese Traditional, English, German, Japanese, Korean.
- Note: OC not included. Must be added to quote and order.

Software option:

· Precision Control software.



Sample introduction:

- Chamber size: 580 (W) x 450 (D) x 150 (H) mm.
- Maximum sample size: 250 (W), 200 (D), 150 (H) mm.
- · Maximum sample weight: 5 kg.

Sample observation:

- High resolution CCD camera dual system (narrow and wide views).
- Maximum field of view: 250 x 220 mm (wide view).
- Optical resolution: 20 µm (narrow view).

Sample measurement:

- Continuous multi-point measurement function with XYZ programmable stage.
- Continuous elemental mapping (max. area 250 x 200 mm).
- Sample height adjustment: laser focus / optical autofocus.
- Collision protection: automatic, laser-based.
- · Air path standard; Helium purge optional.

Dimensions, weight and power:

- Main unit: 750 (W) x 740 (D) x 783 (H) mm, 160 kg.
- Power box: 220 (W) x 451 (D) x 531 (H) mm, 30 kg.
- AC 100 240 V, 50 / 60 Hz, 400W (1.5 m distance).
- The above excludes PC.